



172

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Confirmation No.: 7505

Takei SASAKI et al.

Art Unit: 1756

Application No.: 10/706,971

Examiner: Stephen D. ROSASCO

Filed: November 14, 2003

Attorney Dkt. No.: 101136-00102

For: METHOD AND APPARATUS FOR DRY-ETCHING HALF-TONE PHASE-SHIFT FILMS, HALF-TONE PHASE-SHIFT PHOTOMASKS AND METHOD FOR PREPARATION THEREOF, AND SEMICONDUCTOR CIRCUITS AND METHOD FOR THE FABRICATION THEREOF

RESPONSE UNDER 37 C.F.R. §1.121

MAIL STOP AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Date: **November 1, 2005**

Sir:

This paper is in reply to the Office Action dated August 2, 2005.

Amendments to the **Specification** are presented on page 2.

Amendments to the **Drawings** are discussed on page 3.

Amendments to the **Claims** begin on page 4.

Remarks/arguments are presented on page 9.